

## EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S3	3758	scanning adj probe adj microscope	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/12/11 15:00
S4	586	(scanning adj probe adj microscope). clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/27 15:00
S5	1675	(scanning adj probe adj microscope). ti.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/27 15:00
S6	270	S4 and S5	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/27 15:00
S7	172	S3 and self-assembl\$5	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/27 15:07
S8	1029	S3 and (nanolithography or lithography or etch\$3)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/27 15:08
S9	255	S3 and (nanolithography or lithography or etch\$3).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/27 15:15
S10	6642	scanning adj (probe or tunnel\$3) adj microscope	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/28 10:38
S11	499	S10 and (nanolithography or lithography or etch\$3).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/12/01 16:05

## EAST Search History

S12	2	("6827979").PN.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/27 15:32
S13	9869	force adj microscope	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/27 15:33
S14	14239	S10 S13	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/28 10:39
S15	1943	S14 and etch\$3 and (lithographic or nanolithography or lithography)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/27 15:34
S16	128	S14 and (etch\$3 and (lithographic or nanolithography or lithography)).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/27 15:47
S17	318	(nanolithography or lithography) near3 (dip-pen or pen)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/27 15:41
S18	1197	S14 and (etch\$3).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/27 15:47
S19	38	S14 and (etch\$3 and self-assembl\$4).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/27 15:47
S20	30	("4479831"   "4539089"   "5138174"   "5221415"   "5227626"   "5252835"   "5254854"   "5345815"   "5354985"   "5363697"   "5372930"   "5472881"   "5517280"   "5618760"   "5630932"   "5666190"   "5742377"   "5747334"   "5763933"   "5874668"   "5922214"   "5935454"   "5962736"   "5985356"   "6034348"   "6181097"   "6262426"   "6403382"   "6635311"   "RE35317").PN.	US-PGPUB; USPAT; USOCR	OR	OFF	2006/11/28 10:33

## EAST Search History

S21	300	((weinberger near2 dana)(hong near2 seunghun)(zhang near2 hua)(mirkin near2 chad)).in.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/27 16:03
S22	114	((weinberger near2 dana)(hong near2 seunghun)(zhang near2 hua)(mirkin near2 chad)).in. and microscope	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/27 16:03
S23	80	((weinberger near2 dana)(hong near2 seunghun)(zhang near2 hua)(mirkin near2 chad)).in. and microscope and etch\$3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/30 15:05
S24	5	(microscope and etch\$3 and self-assembl\$4).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/27 16:05
S25	17	S10 and (self-assembl\$4 and etch\$3).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/27 16:34
S26	53	(self-assembl\$4 and etch\$3 and gold).clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/12/11 15:56
S27	2	("6635311").PN.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/28 10:34
S28	6646	scanning adj (probe or tunnel\$3) adj microscope	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/28 10:39
S29	9881	force adj microscope	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/28 10:39
S30	14253	S28 S29	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/28 10:39

## EAST Search History

S31	14253	S30	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/28 10:39
S32	864	S31 and self-assembl\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/28 10:39
S33	13	("4539089").URPN.	USPAT	OR	OFF	2006/11/28 12:27
S34	0	(nib and self-assembl\$4).clm.	USPAT	OR	OFF	2006/11/28 12:28
S35	13	(capillary and self-assembl\$4).clm.	USPAT	OR	OFF	2006/11/28 12:28
S36	18	(tip and self-assembl\$4).clm.	USPAT	OR	OFF	2006/11/28 12:30
S37	6	(microscope and self-assembl\$4).clm.	USPAT	OR	OFF	2006/11/28 12:30
S38	29	(\$5lithography and self-assembl\$4).clm.	USPAT	OR	OFF	2006/11/28 12:31
S39	95	(\$5lithography and self-assembl\$4).clm.	US-PGPUB; USPAT	OR	OFF	2006/11/28 12:34
S40	35	(\$5lithography and self-assembl\$4)	EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/28 12:34
S41	25	(microscope AFM STM SPM) and self-assembl\$4	EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/28 12:37
S42	31	whitesides.in. and self-assembl\$4	EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/28 12:39
S43	24	(tip or nib or (direct adj writ\$3) or (dip adj pen)) and self-assembl\$4	EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/28 12:44
S44	34	(\$5contact adj print\$3) and self-assembl\$4	EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/28 12:47
S45	1027	(\$5contact adj print\$3) and self-assembl\$4	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/28 13:01
S46	2	("5936237").PN.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/28 13:38

## EAST Search History

S47	2	("6180239").PN.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/28 13:38
S49	46	(microscope and nanolithography). clm.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/30 15:11
S50	2	("6635311").PN.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/11/30 15:12
S51	119	(nanolithography or nanoimprint).ti.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/12/01 16:41
S52	3	(nanocontact).ti.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/12/01 16:41
S53	29	((weinberger near2 dana)(hong near2 seunghun)(zhang near2 hua)(mirkin near2 chad)).in. and microscope and nanolithography	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/12/03 17:17